

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Basol et al.
Appl. No. : 10/654,542
Filed : September 2, 2003
For : CONSTANT LOW FORCE
WAFER CARRIER FOR
ELECTROCHEMICAL
MECHANICAL PROCESSING
AND CHEMICAL MECHANICAL
POLISHING
Examiner : Eileen P. Morgan
Group Art Unit : 3723

**CERTIFICATE OF EFS WEB
TRANSMISSION**

I hereby certify that this correspondence, and any other attachment noted on the automated Acknowledgement Receipt, is being transmitted from within the Pacific Time zone to the Commissioner for Patents via the EFS Web server on:

June 19, 2007

(Date)


Tina Chen, Reg. No. 44,606

RESPONSE TO OFFICE ACTION**Mail Stop AF**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action mailed April 19, 2007, please amend the above-captioned application as set forth herein.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.